

## Publikationen

- T. Schweinböck, Günther Benstetter, R. Biberger, Peter Breitschopf, H. Göbel (2008): Intermittent-contact scanning capacitance microscopy versus contact mode SCM applied to 2D dopant profiling. In: *Microelectronics Reliability*, vol. 48 (8-9), pp. 1339-1349.
- B. Knoll, Günther Benstetter, Peter Breitschopf, Werner Frammelsberger (2005): Intermittent contact scanning capacitance microscopy-A novel method for 2D doping profiling. In: *Microelectronics Reliability*, vol. 45, pp. 1568-1571.
- T. Schweinböck, Heiko Ranzinger, P. Reislhuber, Günther Benstetter, Peter Breitschopf, Werner Frammelsberger (2004): AFM-based scanning capacitance techniques for deep sub-micron semiconductor failure analysis. In: *Microelectronics Reliability*, vol. 44, no. 9-11, pp. 1615-1619. DOI: 10.1016/j.microrel.2004.07.079.
- D. Alvarez, T. Schweinböck, S. Schömann, Günther Benstetter, M. Buzzu, Peter Breitschopf, Werner Frammelsberger (2004): New Trends in the application of scanning probe techniques in failure analysis. In: *Microelectronics Reliability*, vol. 44, no. 9-11, pp. 1541-1546. DOI: 10.1016/j.microrel.2004.07.037.
- T. Schweinböck, J. Kiely, Günther Benstetter, Peter Breitschopf, R. Stamp, Werner Frammelsberger (2003): Atomic Force Microscopy Studies of Thin and Ultra-thin SiO<sub>2</sub> Films. Final Report. In: 2nd VDE World Microtechnologies Congress, München.
- D. Liu, Günther Benstetter, Peter Breitschopf, Werner Frammelsberger: Failure analysis of deep sub-micron semiconductor structures and thin films with atomic force microscopy methods. In: First International conference on Engineering Failure Analysis (ICEFA), Lissabon, Portugal.
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- Edgar Lodermeier, Alexander Hofer, D. Liu, Heiko Ranzinger, Günther Benstetter, Peter Breitschopf, W. Bergbauer, Werner Frammelsberger: Raster-Sonden-Mikroskopie (SPM) in der Fehler- und Zuverlässigkeitsanalytik. In: VDE Fehlermechanismen bei kleinen Geometrien, Grainau.
- B. Knoll, Günther Benstetter, Peter Breitschopf, Werner Frammelsberger: Intermittent contact scanning capacitance microscopy - An improved method for 2D doping profiling. In: Nanotech Northern Europe, Helsinki, Finland.
- D. Alvarez, T. Schweinböck, S. Schömann, Günther Benstetter, M. Buzzu, Peter Breitschopf, Werner Frammelsberger: New Trends in the application of scanning probe techniques in failure analysis. In: 15th European Symposium on Reliability of Electron Devices, Failure Physics and Analysis (ESREF), Zürich, Schweiz.
- T. Schweinböck, Heiko Ranzinger, P. Reislhuber, Günther Benstetter, Peter Breitschopf, Werner Frammelsberger: AFM-based scanning capacitance techniques for deep sub-micron semiconductor failure analysis. In: 15th European Symposium on Reliability of Electron Devices, Failure Physics and Analysis (ESREF), Zürich, Schweiz.
- B. Knoll, Günther Benstetter, Peter Breitschopf, Werner Frammelsberger: Intermittent contact scanning capacitance microscopy-A novel method for 2D doping profiling. In: 16th European Symposium on Reliability of Electron Devices, Failure Physics and Analysis (ESREF), Arcachon, Frankreich.